



# A brief introduction to energy dispersive spectrum (EDS) and electron energy loss spectrum (EELS)

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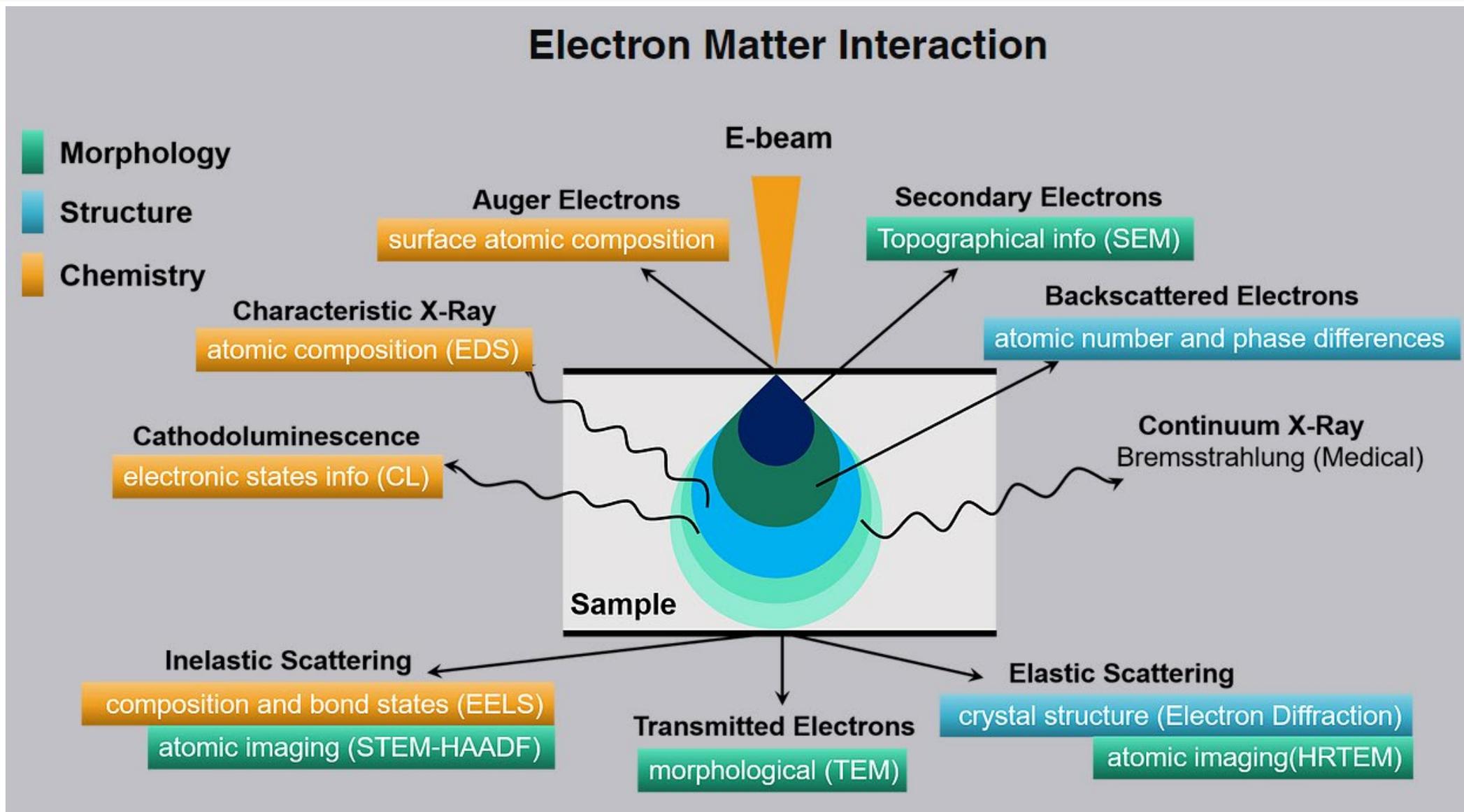
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# Outline

- Principles of EDS and EELS
- Key points/parameters for EDS
- Application of EDS
- Key points/parameters for EELS
- Application of EELS

Quantification methods of EDS and EELS will be covered in future lectures.

# Principles of EDS and EELS



# Key points/parameters for EDS

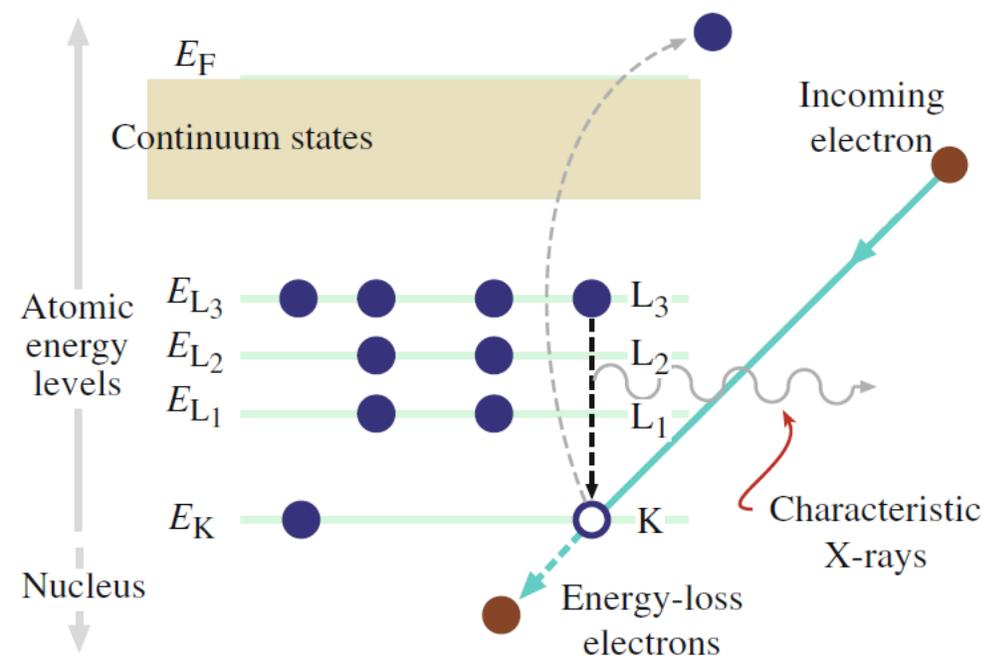
## ➤ X-ray emission

- An ionized atom does not have to lose energy by giving off a characteristic X-ray but can emit an Auger electron instead.
- Fluorescence yield ( $\omega$ ) describes the probability of X-ray versus Auger emission.

$$\omega = \frac{Z^4}{a+Z^4} \quad (\text{for K shell, } a \sim 10^6)$$

For C-K edge,  $\omega \sim 10^{-3}$ ;

For Ge-K edge,  $\omega \sim 0.5$ ;



**That's why EDS is not the best way to analyze the light elements such as Li, Be and B.**



## ➤ Bremsstrahlung X-rays (braking radiation)

- When electrons interact with the Coulomb field of nucleus, there will be substantial momentum changes and it may emit an X-ray during this process.

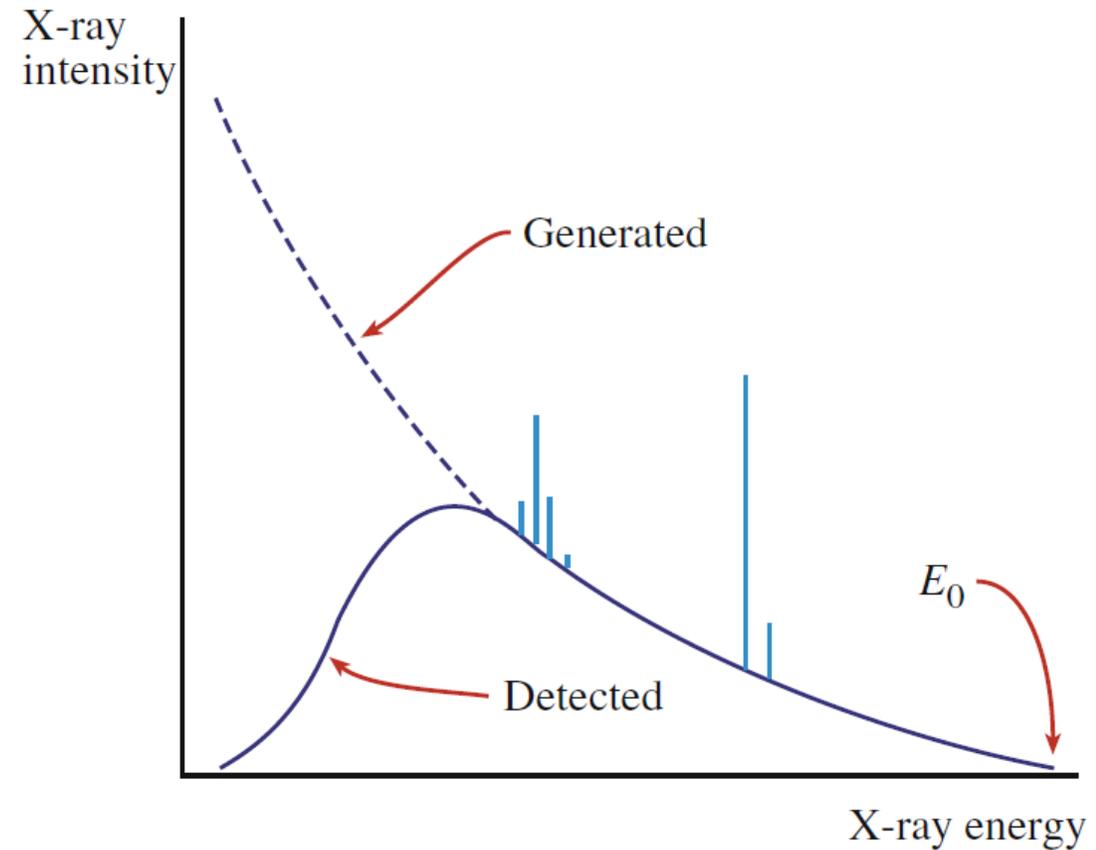
- The approximate expression used is:

$$N(E) = \frac{KZ(E_0 - E)}{E}$$

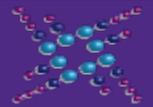
N(E): number of bremsstrahlung photons with energy E;

Z: atomic number; K: Kramers' constant;

E<sub>0</sub>: electron energy



**Bremsstrahlung X-rays contributes to the continuum background.**



➤ Energy resolution ( $\sim 110\text{--}140\text{ eV}$ )

Very low and major limitation

$$R = (P^2 + I^2 + X^2)^{1/2}$$

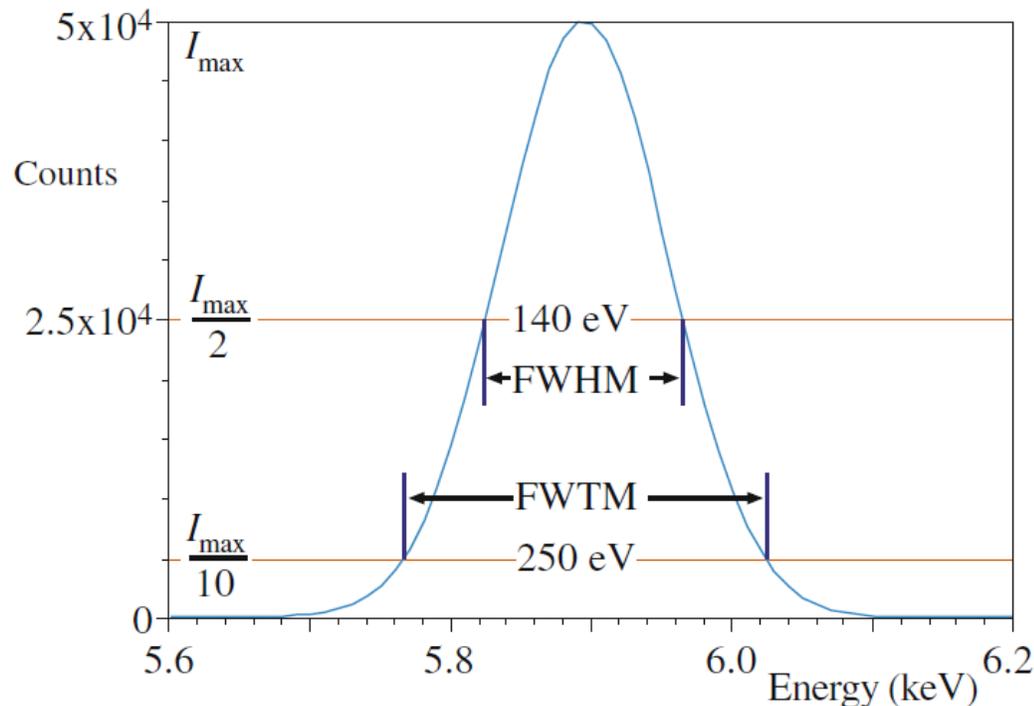
P: Full width at half maximum (FWHM) of a randomized electronic-pulse generator;

X: FWHM-equivalent attributable to detector leakage current and incomplete charge collection;

I: Intrinsic line width of the detector

$$I = 2.35 * (F * \epsilon * E)^{1/2}$$

(F: Fano factor of the distribution of X-ray counts from Poisson statistics;  $\epsilon$ : the energy to create an electron-hole pair in detector; E: the energy of the X-ray line.)



Estimate the energy resolution of Si detector:

- Assume there is no leakage, and the electronics produce no noise ( $P=X=0$ )
- $F = 0.1$ ;  $\epsilon = 3.8\text{ eV}$ ; for Mn  $K\alpha$  line,  $E = 5.9\text{ keV}$
- $R = I = 111\text{ eV}$

## ➤ Spatial resolution

The spatial resolution (R) of EDS is governed by the beam-specimen interaction volume, which is a function of the incident-beam diameter ( $d_t$ ) and the beam spreading (b).

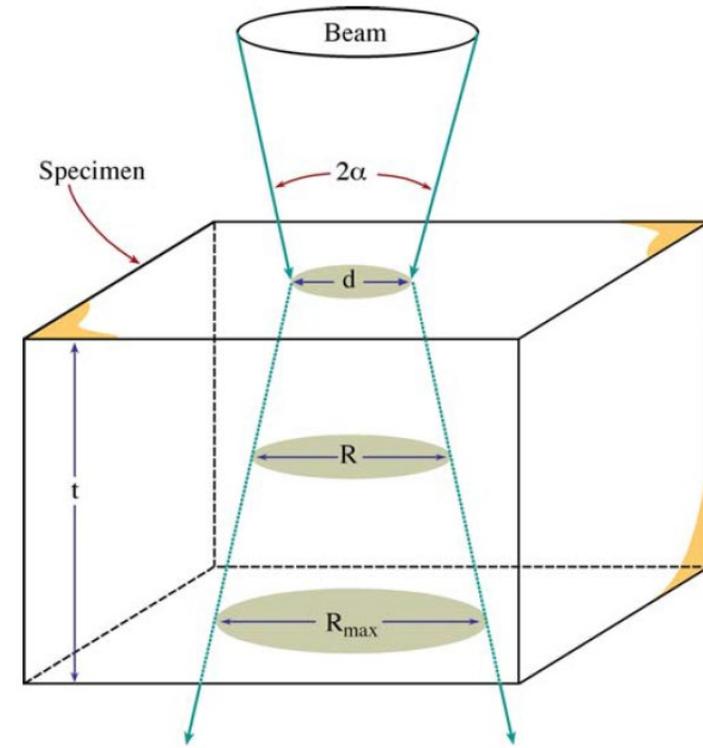
$$R = \frac{d + R_{max}}{2}; R_{max} = (b^2 + d_t^2)^{1/2}; b = 8 \times 10^{-12} \frac{Z}{E_0} * N_v^{1/2} * t^{3/2}$$

Z: atomic number;

$E_0$ : incident electron energy in keV

$N_v$ : number of atom/ $m^3$

t: foil thickness

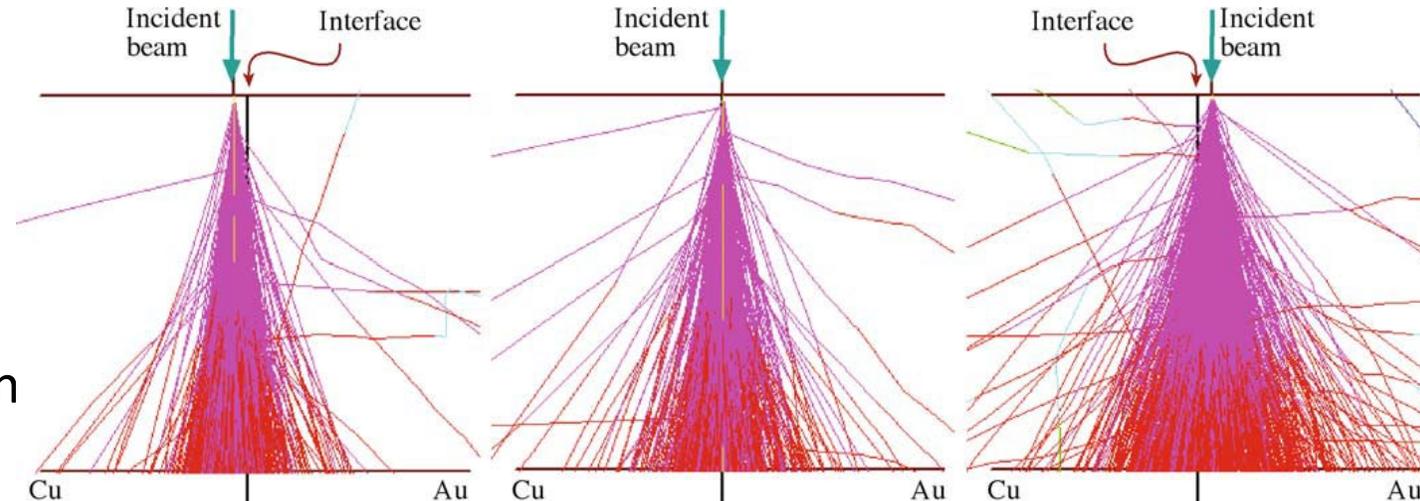


$$d_t = (d_g^2 + d_s^2 + d_d^2)^{1/2}$$

$d_g$ : beam spread due to gun

$d_s$ : beam spread due to spherical aberration

$d_d$ : beam spread due to diffraction limitation



➤ **Time constant ( $\tau$ )** Usually using a shortest  $\tau$  to maximize the count rate

- $\tau$  ( $\sim 5$ - $100 \mu\text{s}$ ) is the time allowed for the analog processor to evaluate the magnitude of the charge pulse.
- Shorter  $\tau$  will give a larger counting rate but will give a greater error in assignment of a specific energy to the pulse (poorer resolution).

➤ **Dead time**

- Dead time is when the detector is not counting X-rays but processing the previous photon.

$$\text{Dead time in \%} = \left( 1 - \frac{\text{output count rate } (R_{out})}{\text{input count rate } (R_{in})} \right) * 100\% = \left( \frac{\text{clock time} - \text{live time}}{\text{clock time}} \right) * 100\%$$

Live time is when the detector is ready to detect an X-ray and not processing any signal;

- Excess of 50-60% indicating the detector is saturated with X-rays and collection becomes increase inefficient. You should find thinner area and reduce the beam current.
- Less than 3% indicating the X-ray signal is not enough. This is the normal case for TEM sample.

➤ **Collection angle ( $\Omega$ )** **The larger the better.**

- Solid angle  $\Omega = \frac{A \cdot \cos \delta}{S^2}$  (usually  $< 0.5$  sr)

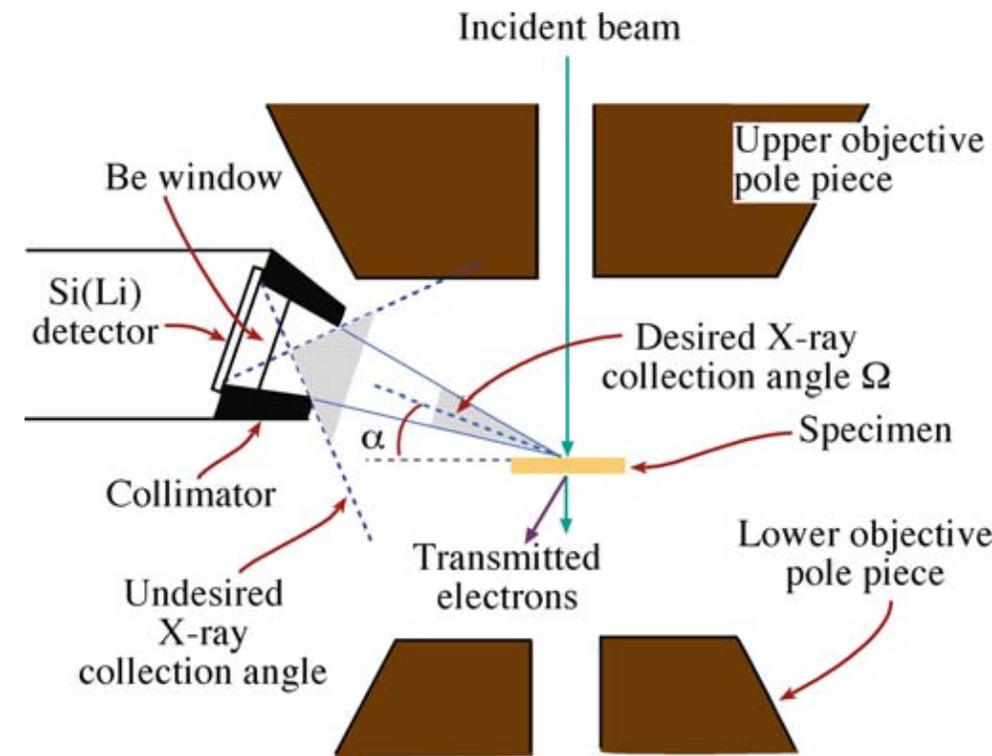
A: the active area of the detector (30-100 mm<sup>2</sup>);

$\delta$ : angle between the normal to detector face and a line from detector to specimen; (normally,  $\delta=0$ )

S: distance from the analysis point to detector face;

➤ **Take-off angle ( $\alpha$  usually 15° )**

- Detector position was fixed. You can only change this slightly by tilting your sample
- Sample tilt can reduce P/B (peak/background) ratio and increase spurious effects





## Common artifacts from EDS detector

- Si escape peak (signal detection artifact)

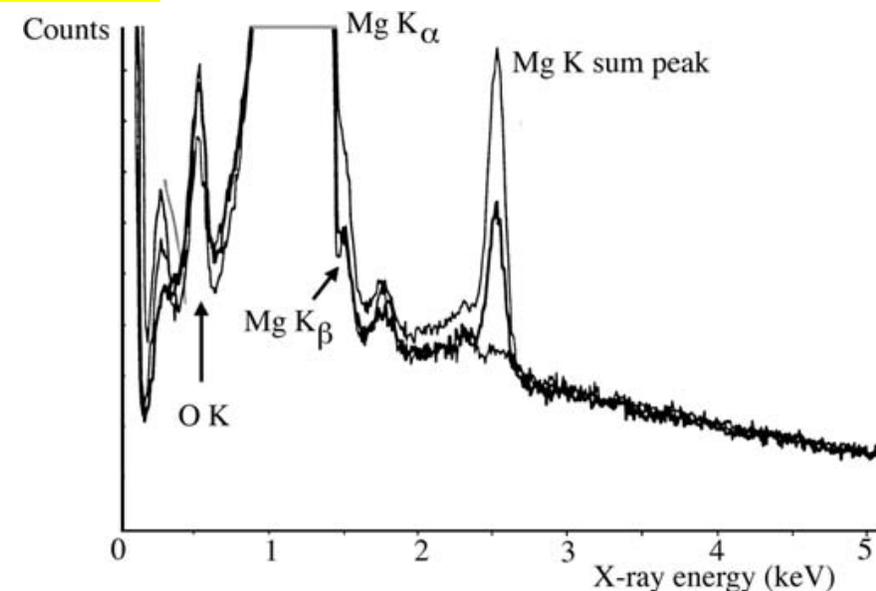
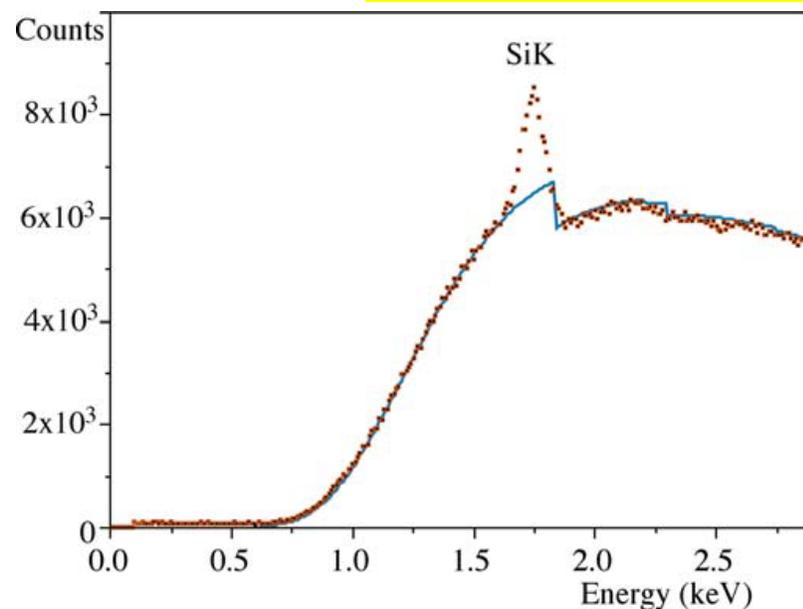
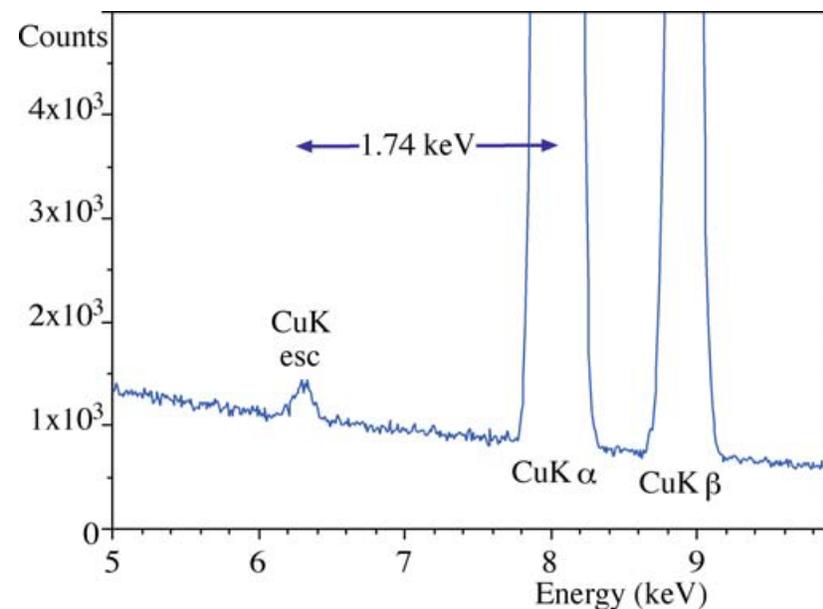
Detector is not a perfect sink. Incoming photon with energy  $E$  is not transformed into electron-hole pairs but fluoresces a Si  $K\alpha$  X-ray with a 1.74 keV energy.

- Internal fluorescence peak (signal detection artifact)

Incoming photons fluoresce atoms in the dead layer of the detector and result in Si  $K\alpha$  peak

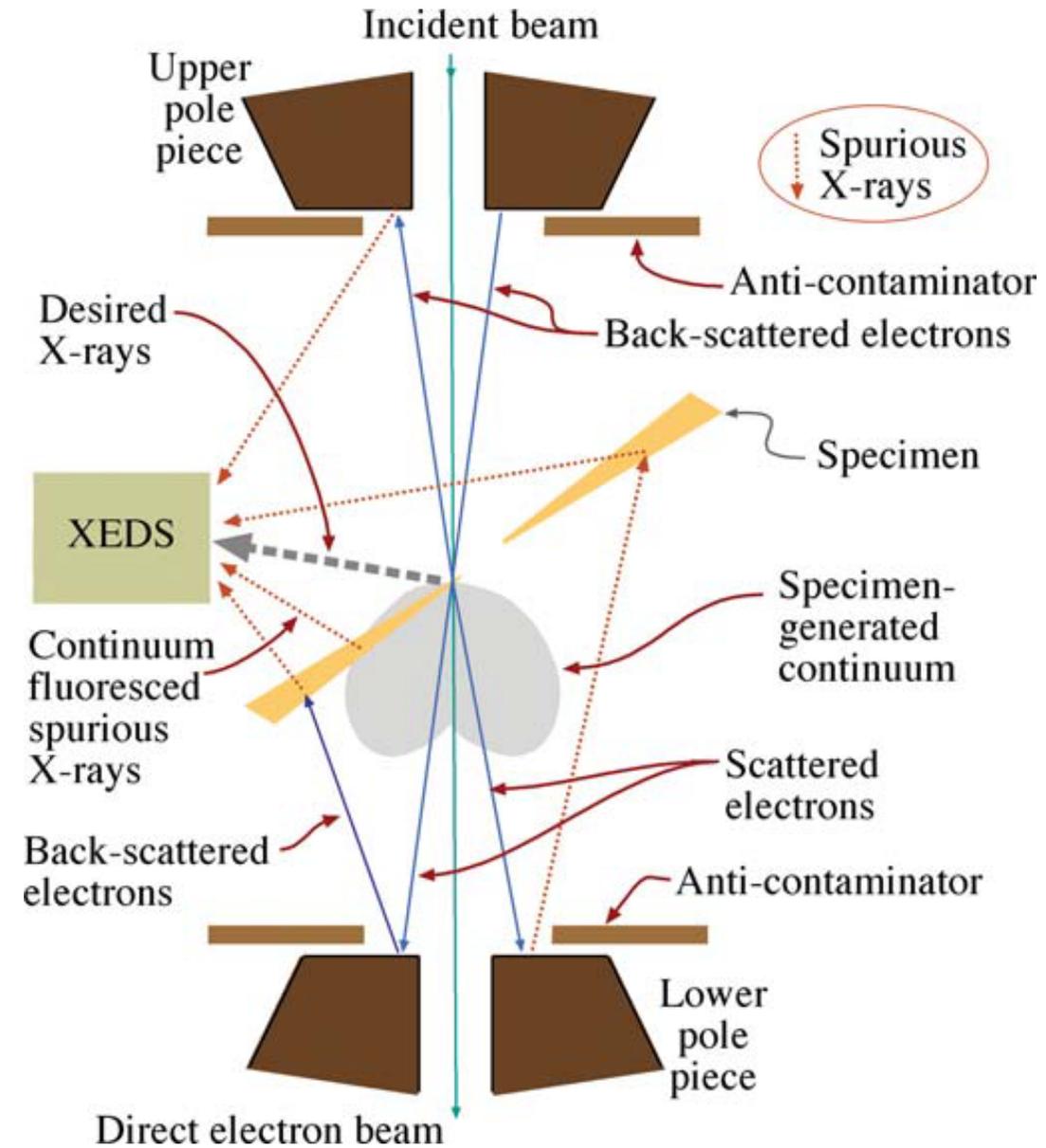
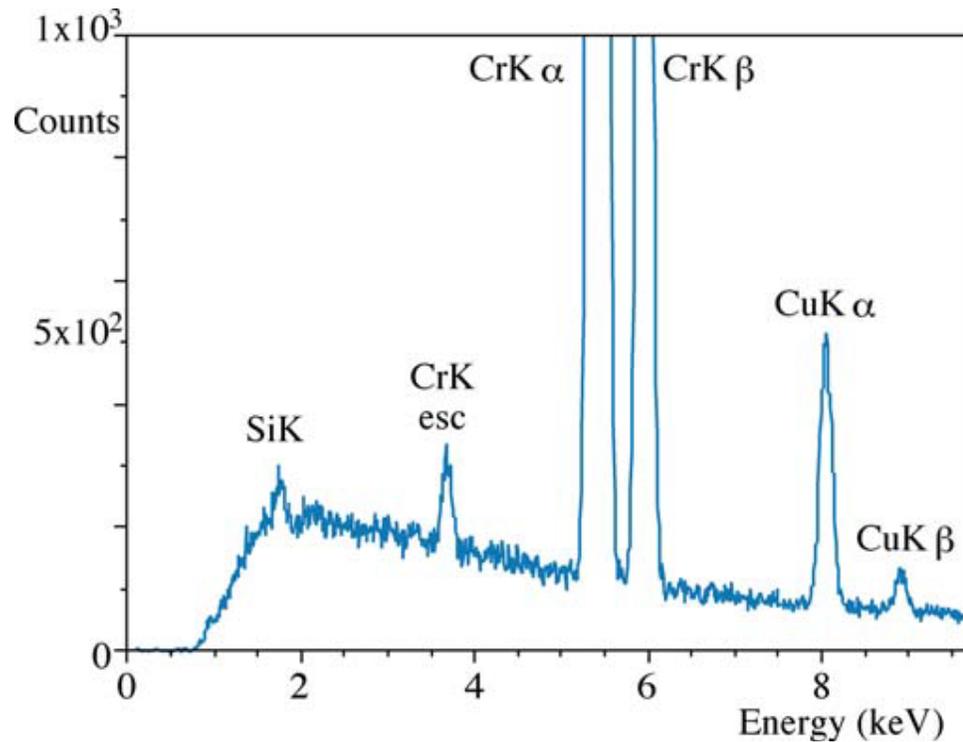
- Sum peak (signal processing artifact)

Sum peak occurs when the count rate exceeds the electronics' ability to discriminate all the individual pulses and so-called 'pulse pile-up'. **Reduce the dead time!!**



# System X-rays

- Cu is everywhere
- Remember to remove the objective aperture before taking EDS signal
- Operate as close to zero tilt as possible

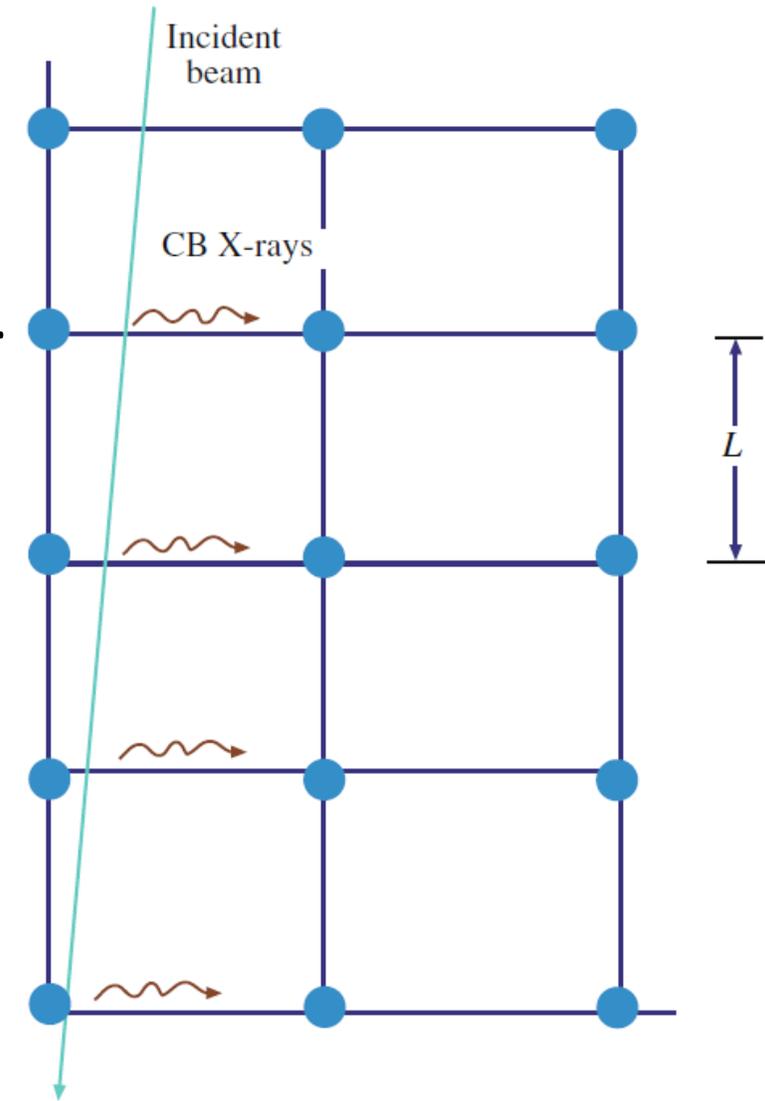
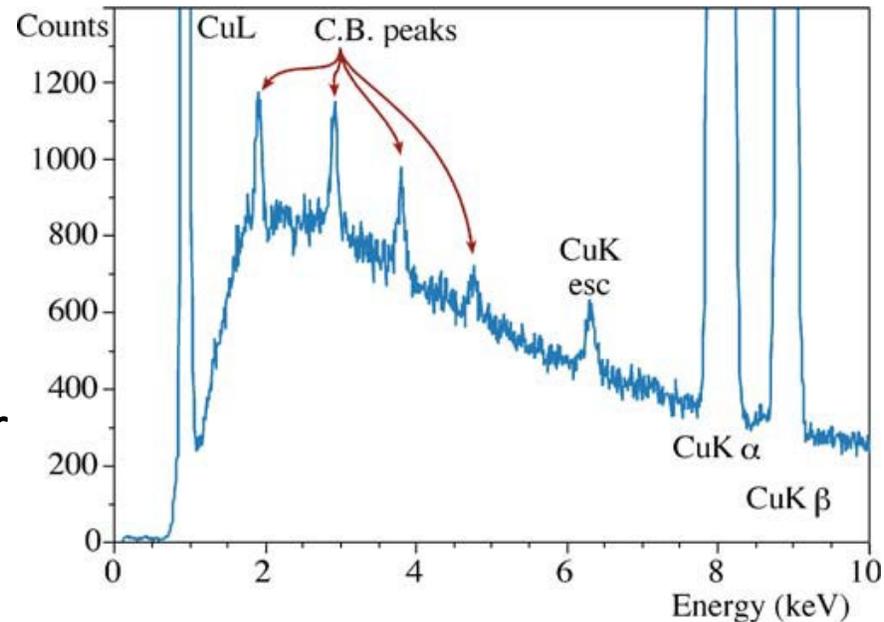


# Coherent Bremsstrahlung (CB)

- Continuous bremsstrahlung spectrum usually happens bulk polycrystalline materials by electrons with lower energy (< 30 ekeV)
- Within TEM, for single crystalline specimens, CB likely will occur.

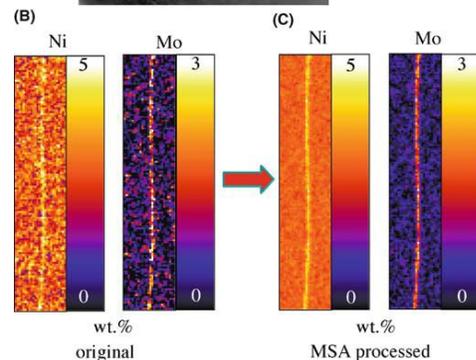
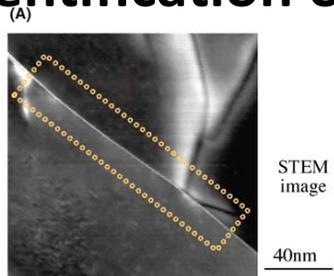
$$E_{CB} = \frac{12.4\beta}{L(1-\beta\cos(90+\alpha))}$$

$\beta$ : electron velocity divided by the velocity of light  
 $L$ : Lattice spacing in the beam direction  
 $\alpha$ : take-off angle of the detector

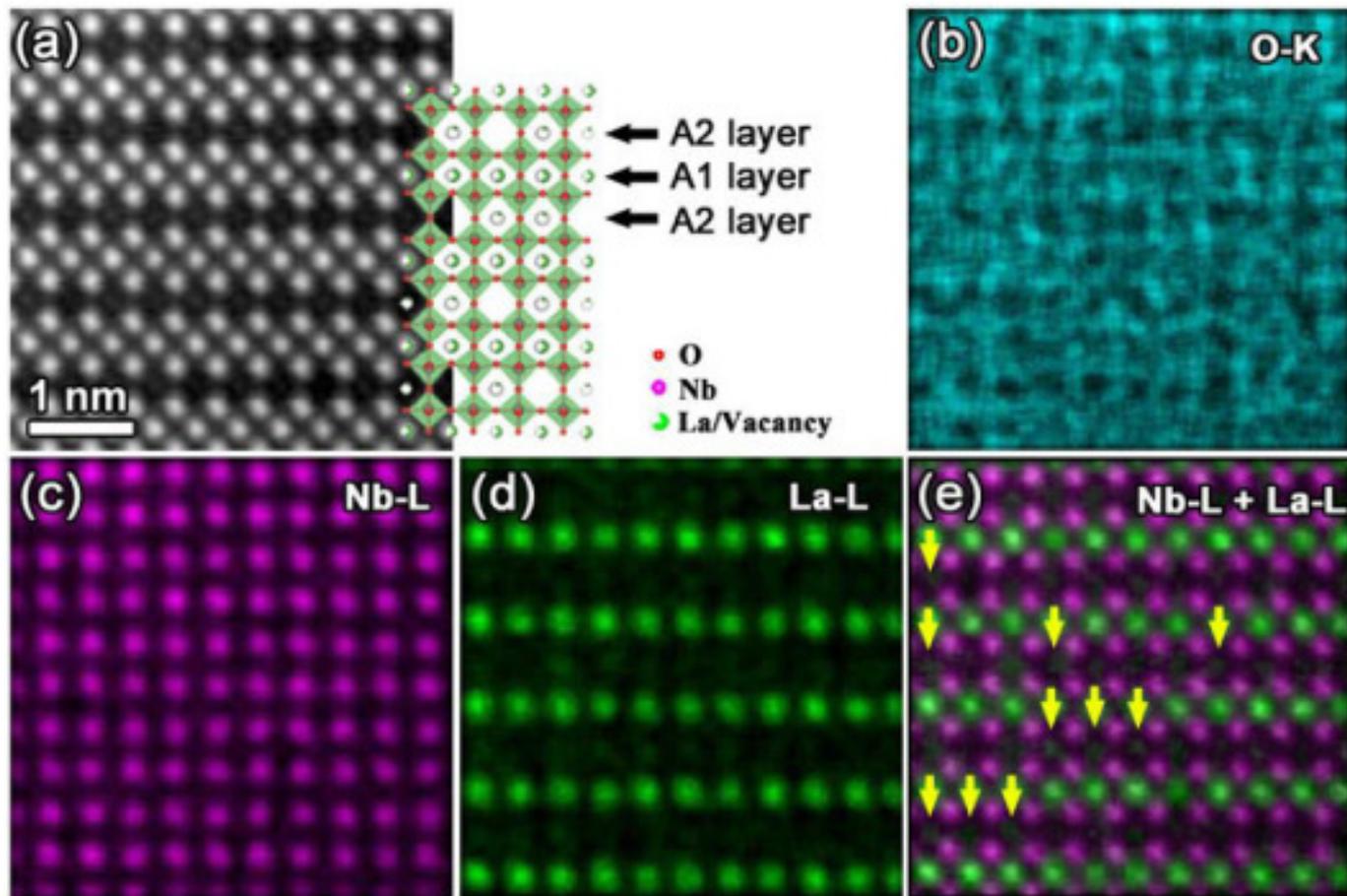
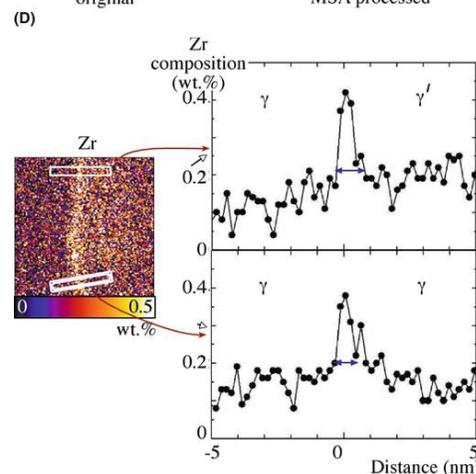


# Application of EDS

## Identification of the elements and distribution



Elements distribution along grain boundary within a low alloy steel.



Revealing the La-rich and La-deficient within the solid electrolyte directly.

# Key points/parameters for EELS

## ➤ Cross-section differential

Cross-section differential of the inelastic scattering:

$$\frac{d^2\sigma}{d\Omega dE} \approx \frac{8a_0^2 R^2}{Em_0 v^2} * \left( \frac{1}{\theta^2 + \theta_E^2} \right) * \frac{df}{dE}$$

$\sigma$ : Cross-section of the inelastic scattering;

$\Omega$ : solid angle;

$a_0$ : Bohr radius, 0.53 Å;

$E$ : Electron loss energy

$m_0$ : rest mass of electron;

$R$ : Rydberg energy, 13.6 eV;

$v$ : velocity of electrons

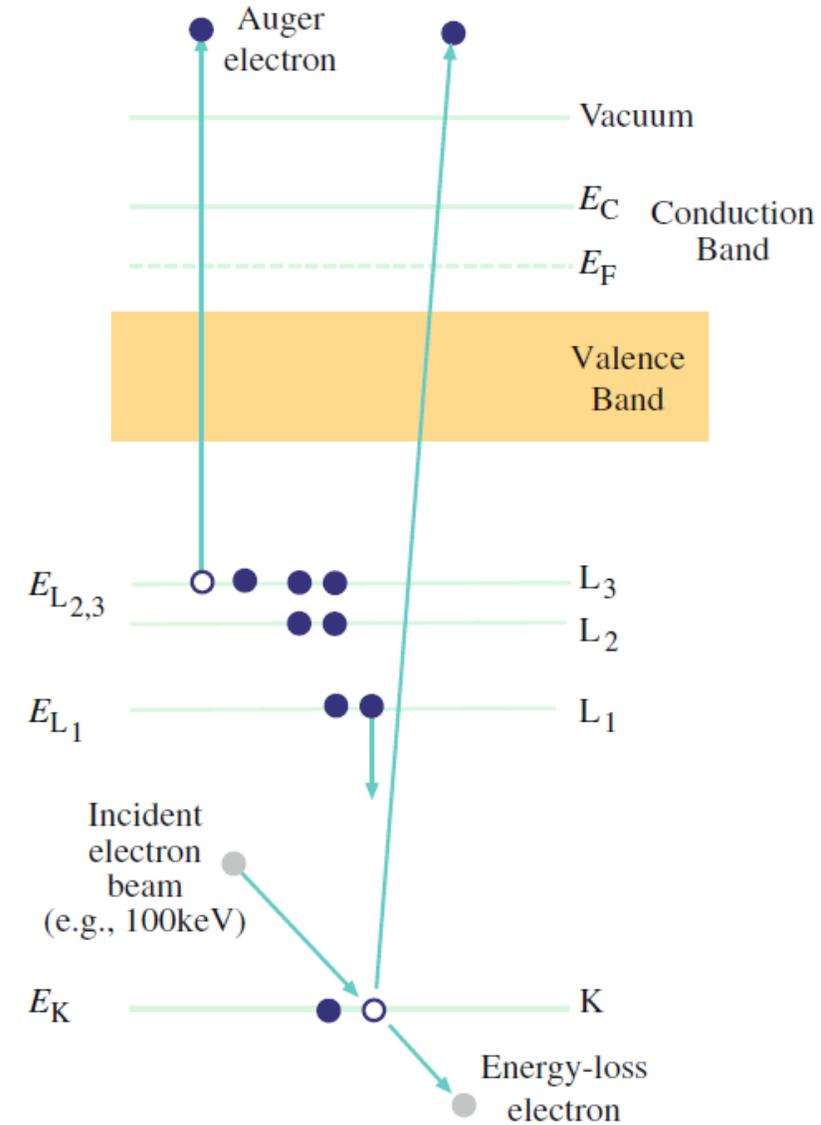
$\theta_E$ : characteristic angle equaling approximately  $E/2E_0$ ;

$E_0$ : Electron energy of the incident electrons

$\theta$ : scattering angle;

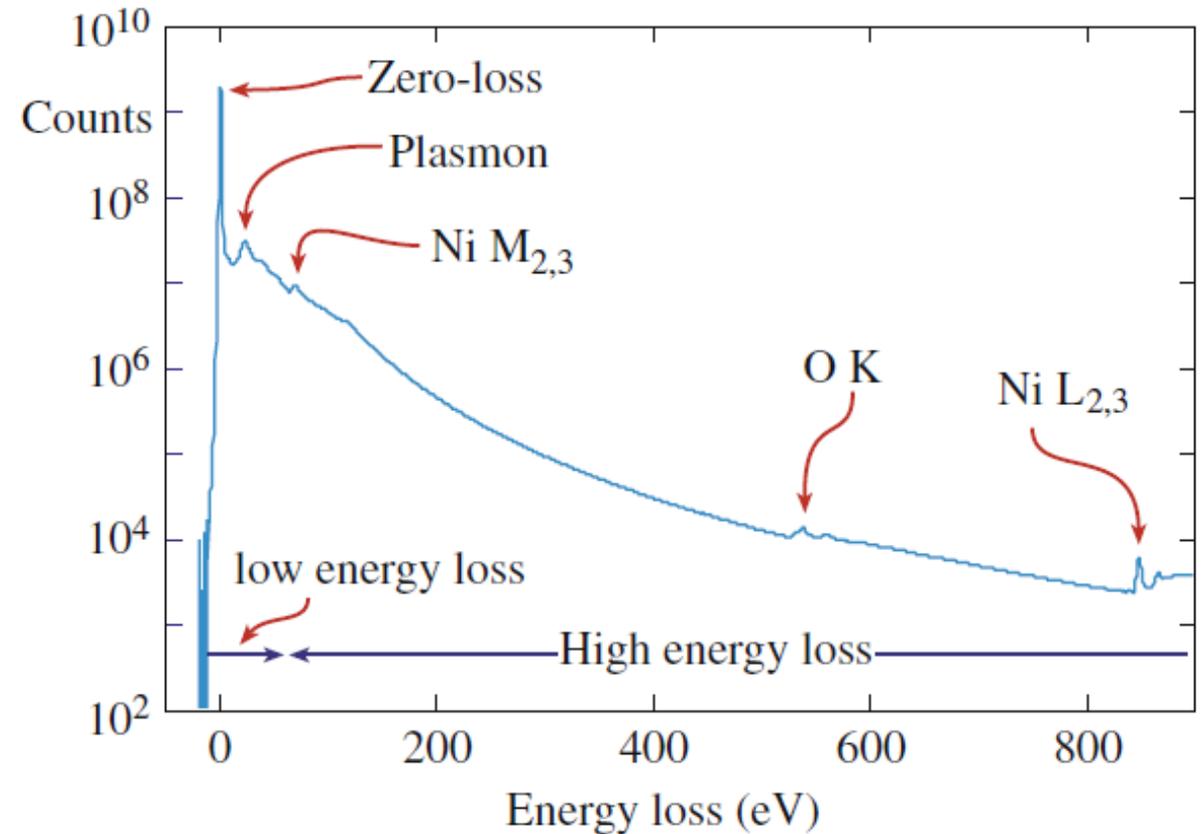
$df/dE$ : Generalized Oscillator Strength

- 1> Higher energy loss has smaller cross-section—Lower signal;
- 2> Lower incident electron energy has larger cross-section of scattering—Higher signal



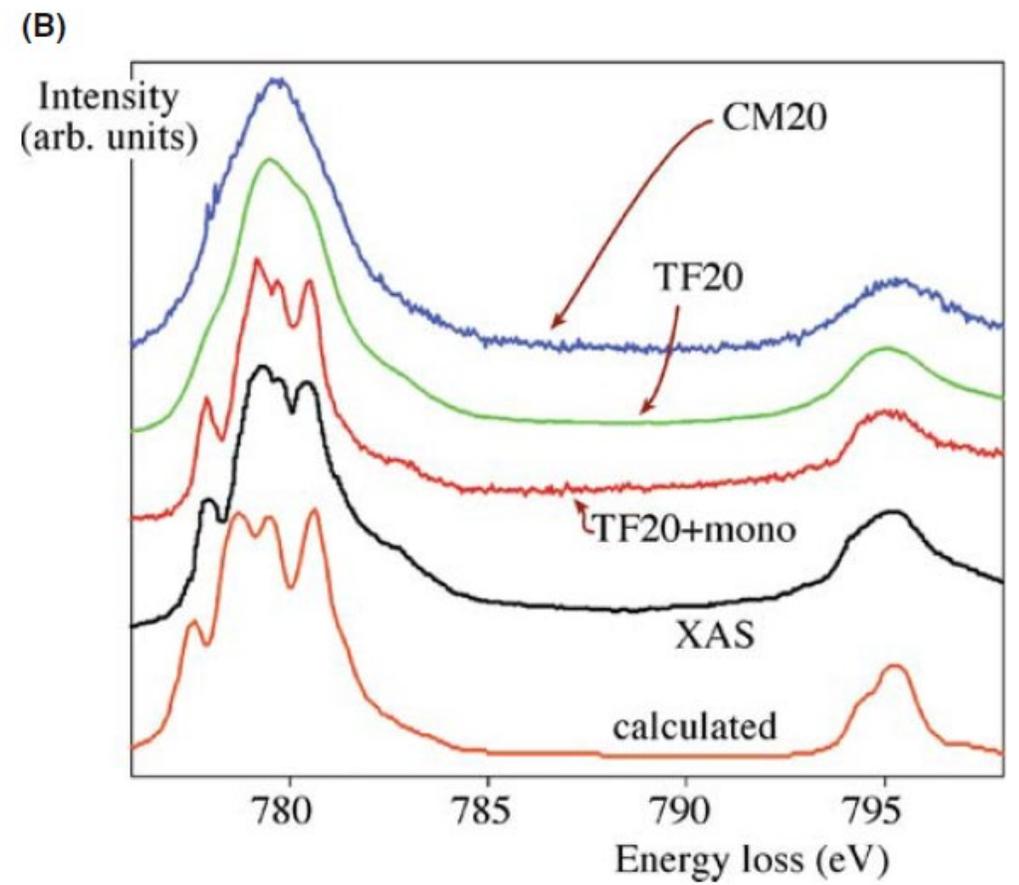
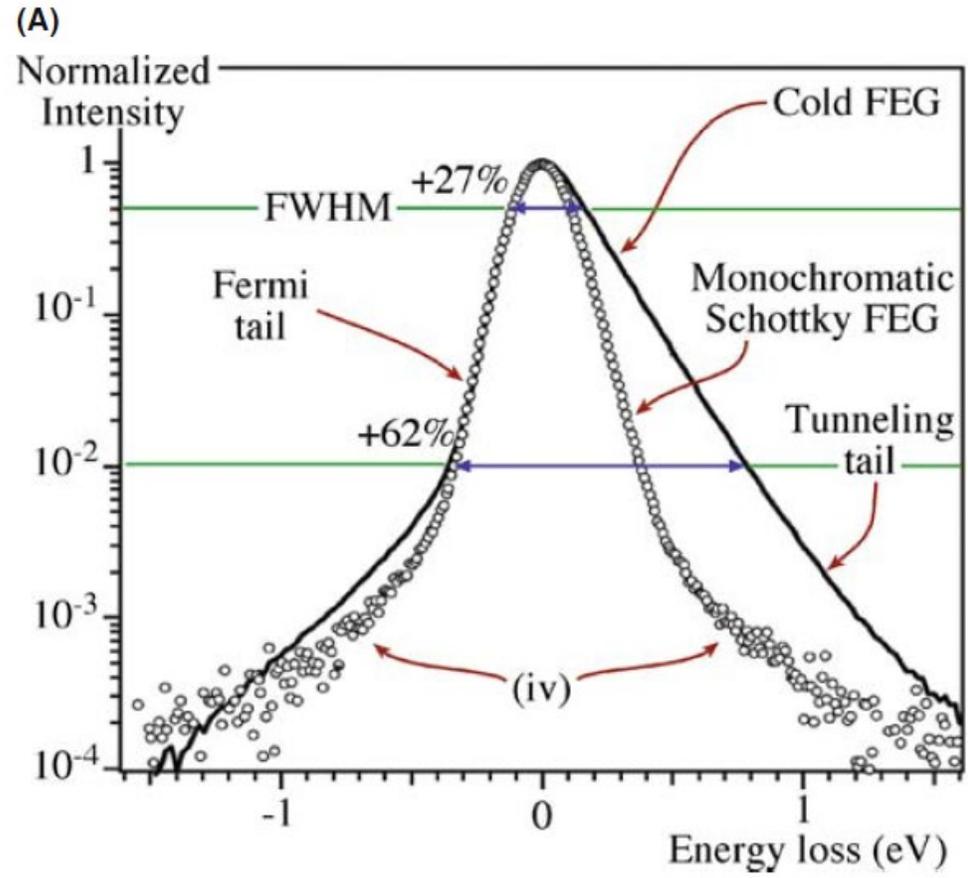
## ➤ Energy-loss spectrum

- Zero loss peak (Very intense)
- Low loss regime containing the plasmon peak is relatively intense.
- The ionization edges are relatively low intensity compared to the background.
- Overall intensity drops rapidly with increasing energy loss, reaching negligible levels above  $\sim 2\text{keV}$



# Energy resolution

- Higher energy resolution can give you more details.
- The electron gun usually dictates the ultimate energy resolution. (W: 3eV; LaB6: 1.5eV; Cold FEG Gun: 0.35 eV)
- Monochromators can give you very high energy resolution but reduce the signals.

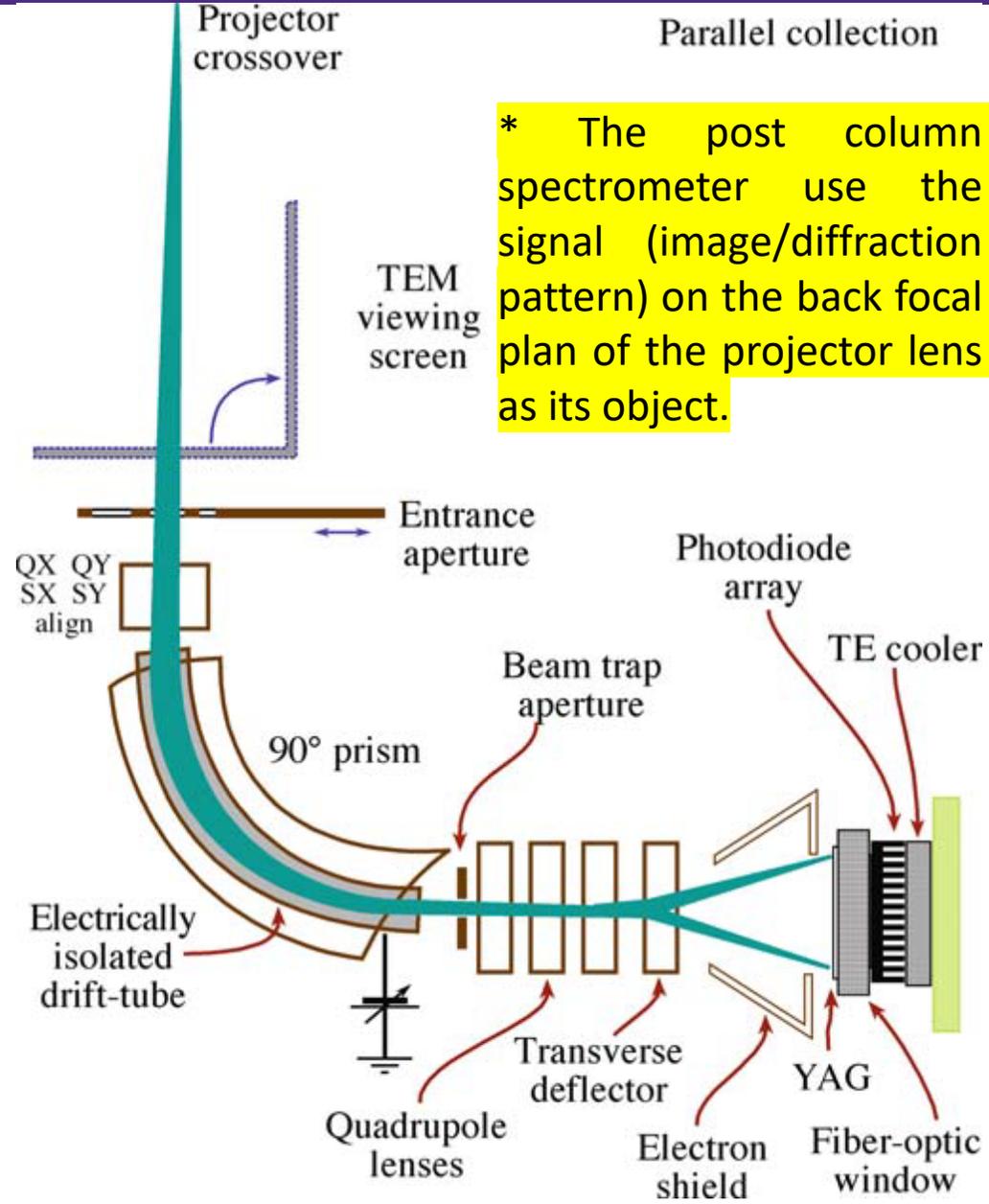
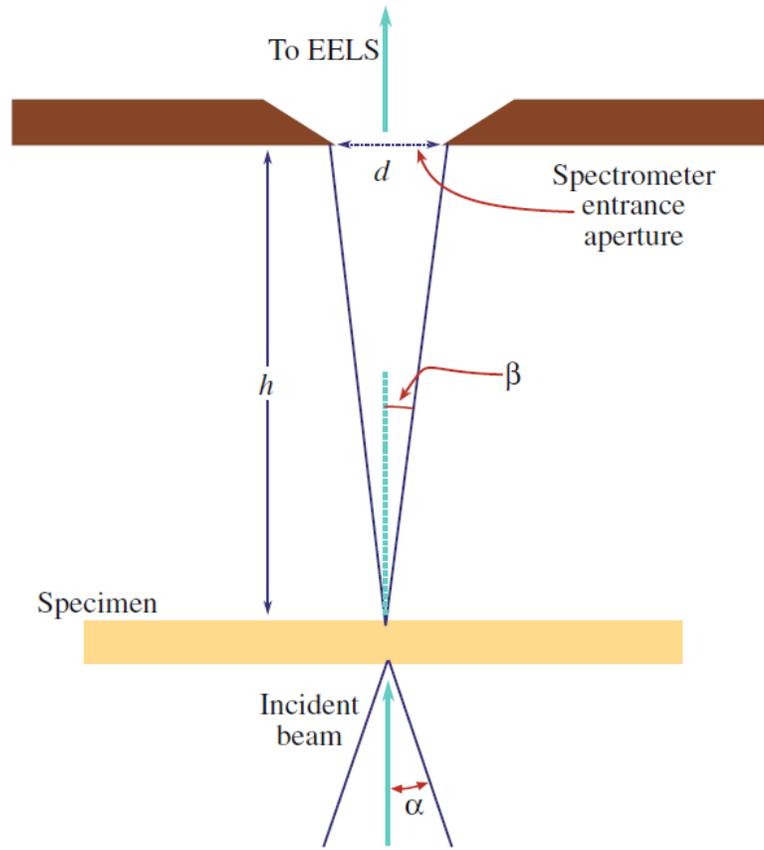


# Collection angle ( $\beta$ )

- For dedicated STEM

Cross-section differential of the inelastic scattering:

$$\beta \approx \frac{d}{2h}$$



# TEM-imaging mode (diffraction coupling)

If there is no objective aperture:

$$\beta \approx \frac{r_0}{L}$$

$r_0$ : maximum radius of the diffraction pattern in the focal plane of the spectrometer; typically  $\sim 5 \mu\text{m}$

$L$ : camera length;

$$L \approx \frac{D}{M}$$

$D$ : distance from the projector crossover to the recording plan  $\sim 0.5 \mu\text{m}$

$M$ : magnification of the image in the recording plan

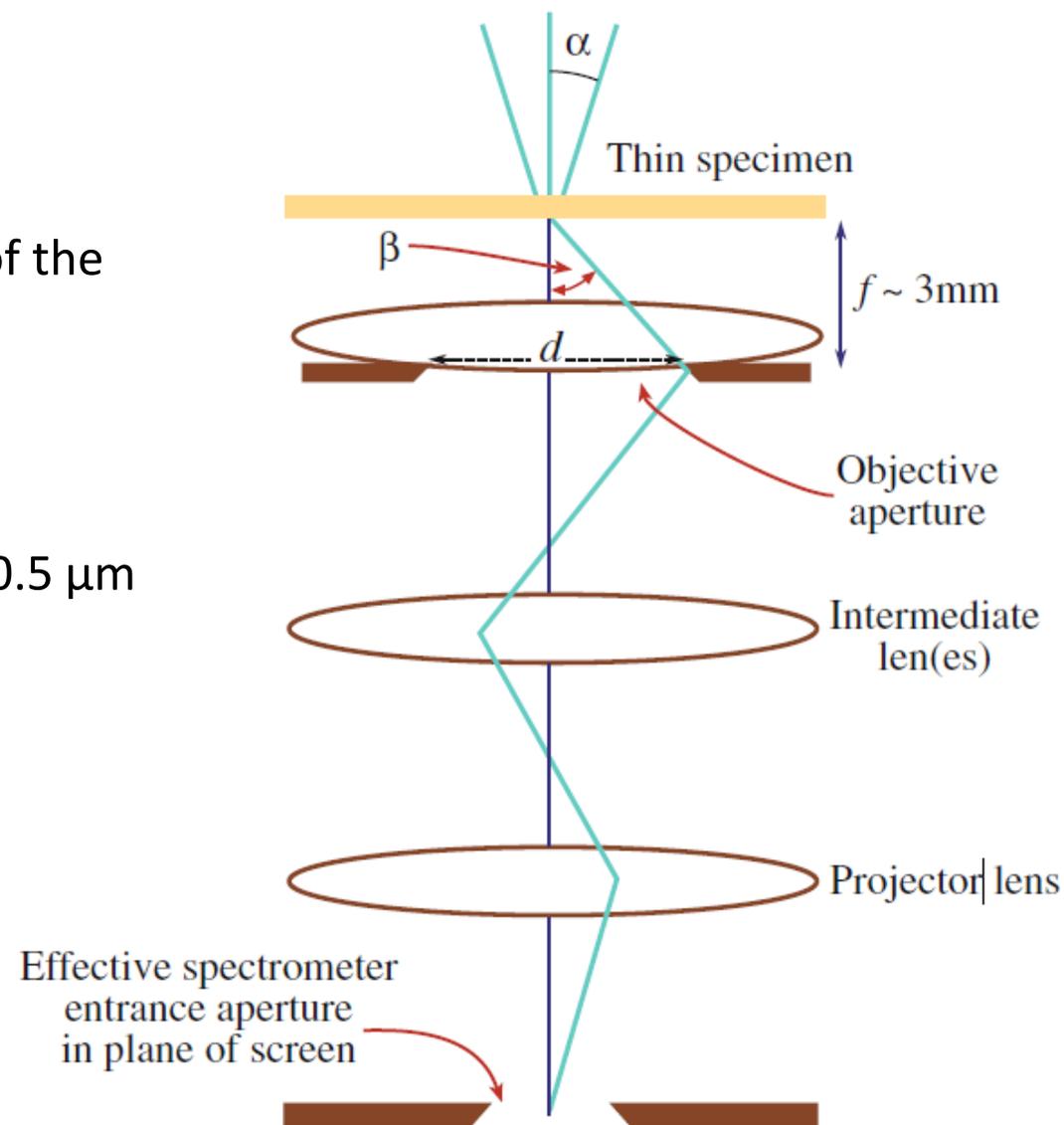
If  $M=10000$ ,  $D=0.5 \mu\text{m}$ ,  $\beta$  is around 100mrad.

If there is an objective aperture:

$$\beta \approx \frac{d}{2f} \text{ (if } d=30 \mu\text{m, } f=3 \text{ mm, } \beta \text{ is around 5 mrad)}$$

$d$ : diameter of the objective aperture;

$f$ : focal length of the objective lens;



# TEM/STEM diffraction mode (image coupling)

Collection angle is mainly limited by the entrance aperture

$$\beta = \frac{d_{eff} * 2\theta_B}{2b} = \frac{D}{D_A} * \frac{d}{L}$$

$\theta_B$ : Bragg angle

b: distance between 000 and hkl

$d_{eff}$ : effective aperture diameter

L: camera length on the recording plane

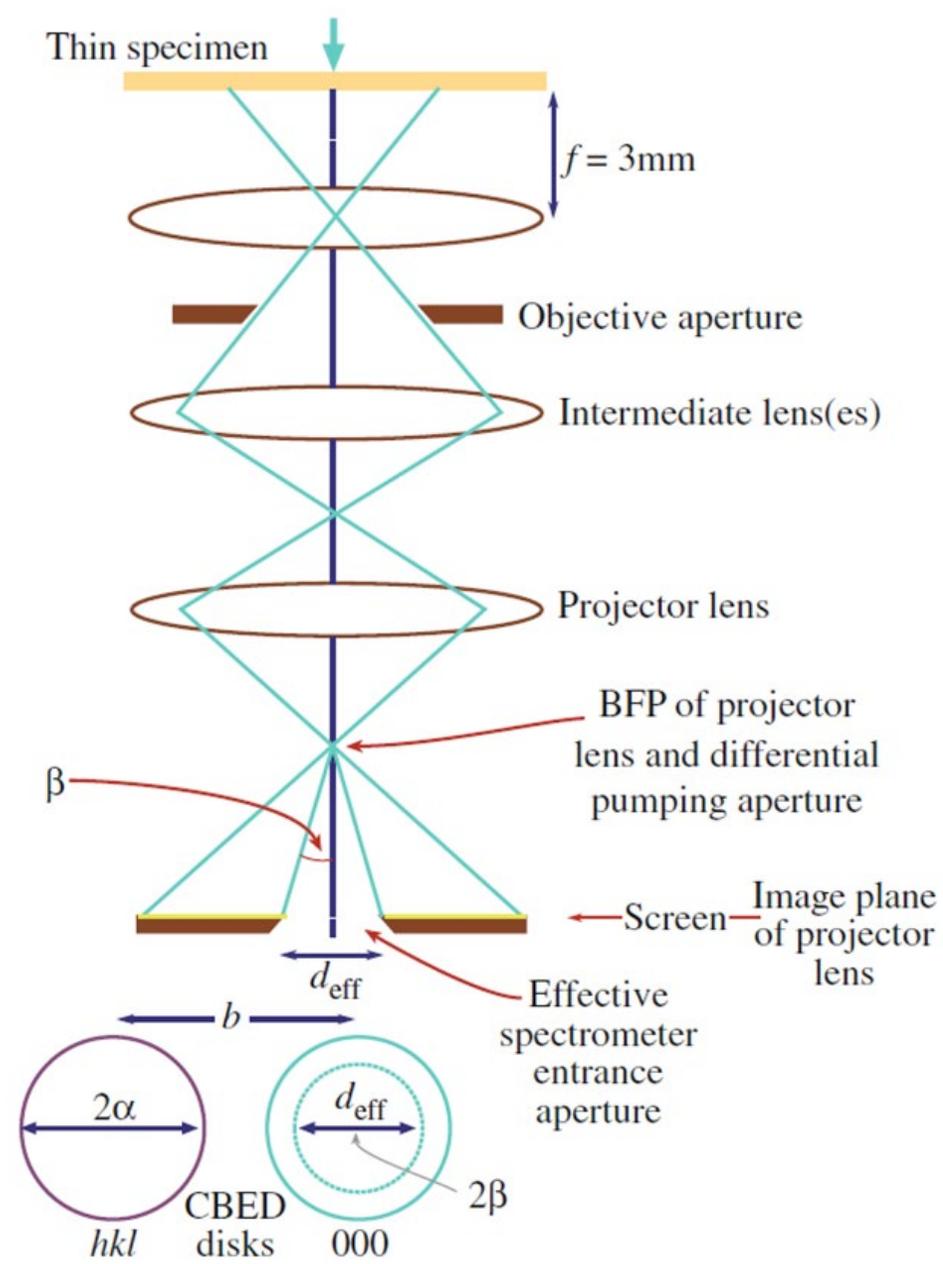
$$d_{eff} = \frac{d * D}{D_A}$$

D: distance from projector crossover to the recording plane (Varies)

$D_A$ : distance between the crossover and entrance aperture (typically 610 mm for Gatan EELS)

For example:

If D=500 mm, L=800mm, GIF aperture 5mm,  $\beta$  is around 5mrad.



## ➤ Characteristic angle and cut-off angle

- Characteristic angle

$$\theta_E \approx \frac{E}{2E_0} \text{ (E: electron energy loss; } E_0 \text{: incident electron energy)}$$

\* The characteristic scattering angles for core-loss electrons range from  $\sim 0.2$  to 10 mrad.

\* Collection angle  $\beta > 2-3 \theta_E$ ; **A smaller  $\beta$  will cut off intensity in spectrum**

- Cut-off angle (above which the scattering intensity is zero)

$$\theta_c = (2 * \theta_E)^{\frac{1}{2}}$$

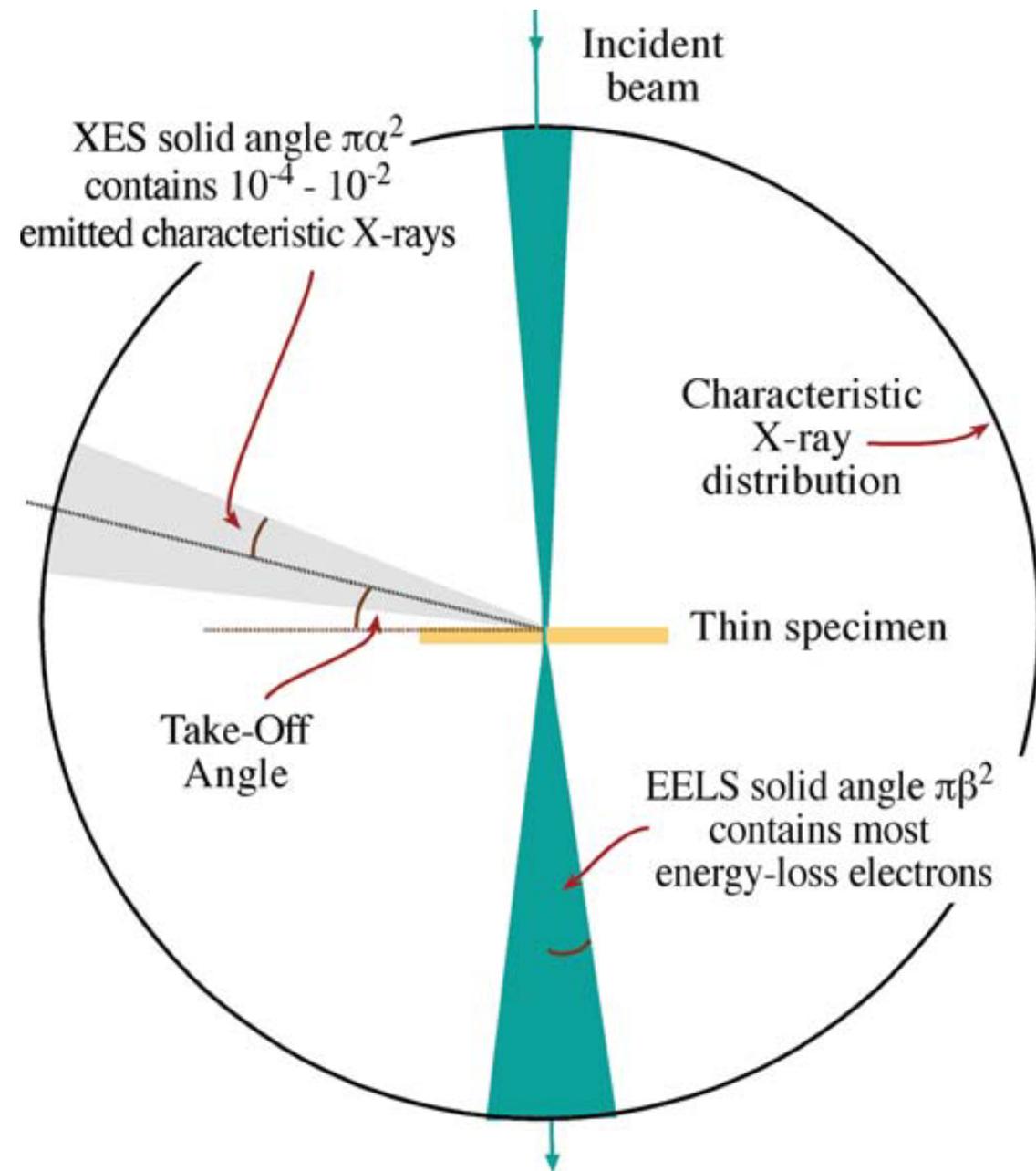
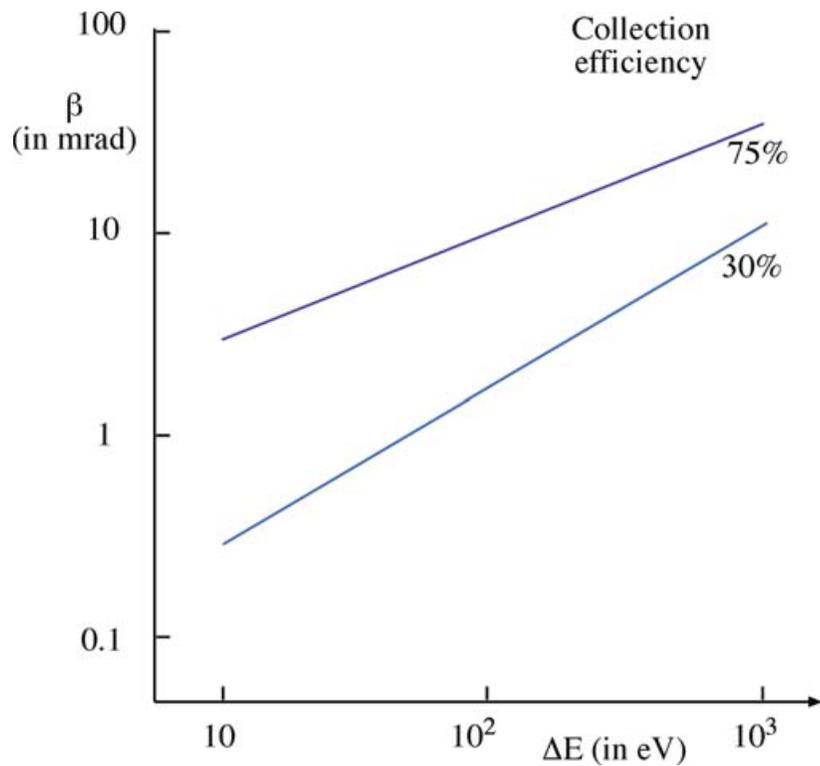
\* Be careful to calculate this angle in radians but not in milliradians.

\* The characteristic cut-off angles for core-loss electrons range from  $\sim 25$  to 200 mrad;

\* **Too large  $\beta$  will include many unwanted electrons.**

# Detection efficiency

- Ionization-loss electrons are very strongly forward-scattered.
- Detection efficiency of EELS is very high (50-100%)
- Detection efficiency of EDS is usually inefficient.



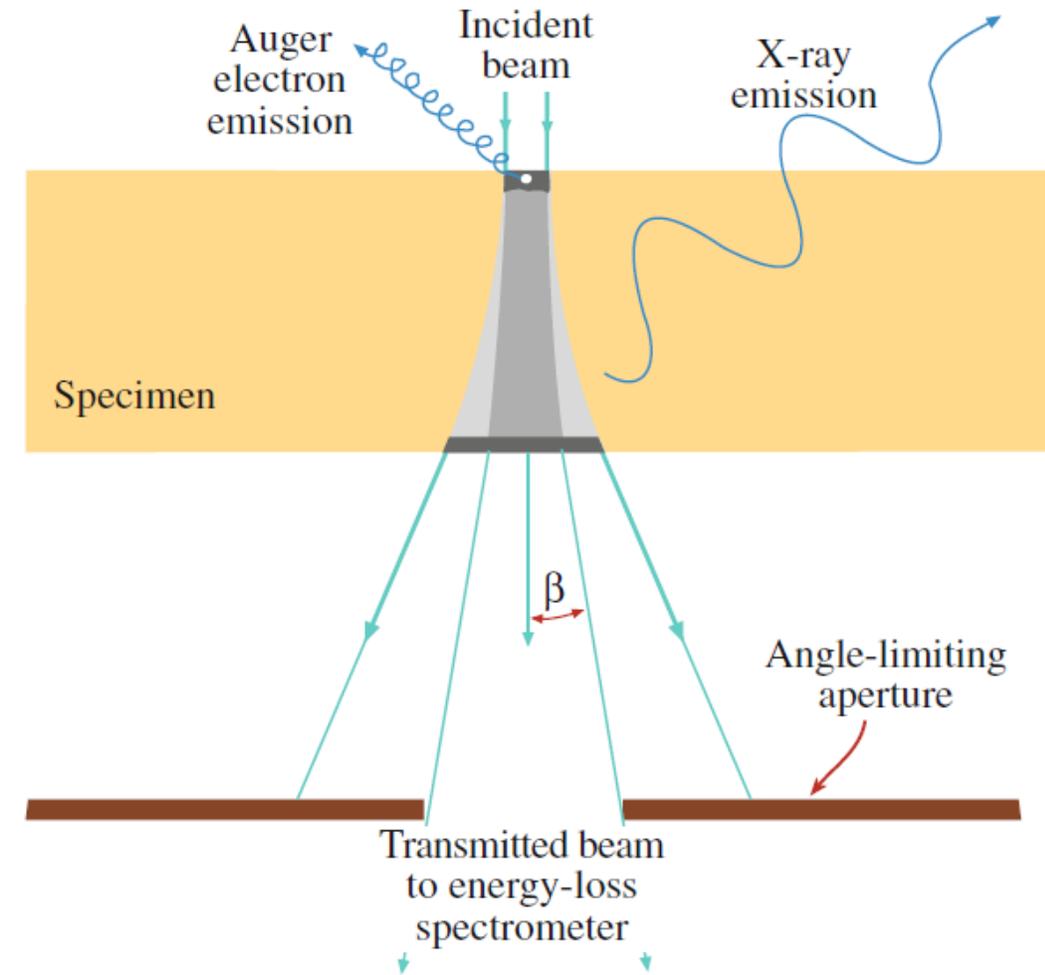
## ➤ Spatial resolution

- In STEM/diffraction mode, the resolution is mainly limited by the size of the probe.
- In TEM imaging mode, the selecting aperture (e.g., spectrometer entrance aperture and its effective size at the plane of the specimen) is a limited factor.
- Delocalization **which is the ejection of an inner-shell electron by the passage of a high-energy electron some distance from the atom** is another limiting factor.

Diameter  $d_{50}$  contains 50% of the inelastic intensity.

$$d_{50}^2 = \left(\frac{0.5\lambda}{\theta_E^{0.75}}\right)^2 + \left(\frac{0.6\lambda}{\beta}\right)^2$$

For energy loss  $E = 50$  eV,  $d_{50}$  is around 1 nm. For  $E = 300$  eV,  $d_{50}$  is around 0.4 nm.



That is why it is very challengeable for getting the atomic resolution EELS map using light elements (e.g. C and B).

# Application of EELS

- Identification of specific elements and concentration
- Identification of valence state of the elements.
- Determination of band gap, plasmon and other physics related phenomenon...
- .....

**Thank you for your attention!**

**Q.&A.**